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In this article the role and value of innovative projects in the field of creation and perfection of scientific and technical potential of the state are shown, the basic problems of realizability of innovative projects in the sphere of research and development are formulated and offers aimed at their implementation are worked out. The analysis of the structure and volumes of internal expenses for researches and development on various sources of financing is made and the complex of actions directed at creation of conditions for normal development of the innovative environment and increase of a level of realizability of innovative projects in the sphere of research and development is worked out.

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The question of movement of pores formed on an interface bounded of silicon wafers of sensitive elements (SE) of microelectromechanical systems (MEMS) used by manufacture SE MEMS is considered. Influence of pores on work of sensitive elements MEMS is described. The design procedure of process of closing of pores, based on the theory of change of volume and the form of a pore and movement of her centre of gravity near to border of thin a silicon layer caused by volumetric diffusion of vacancies is offered. Influence superficial nanolayers on stiffness of bracket of silicon sensitive element MEMS is analysed.

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